ABSTRACT OF THE DISCLOSURE

A photo-fabrication apparatus (1) comprises a stage (2) for holding a photosensitive member (9) which is a substrate coated with a photosensitive material, a head part (3) for emitting a spatially-modulated light beam to said photosensitive member (9) and a computer (5). The head part (3) has a DMD (32) having a plurality of micromirrors arranged in a two-dimensional array, and a light beam from a light source (31) is reflected on only some of the group of micromirrors in the DMD (32) which have a predetermined tilt angle and led onto the photosensitive member (9). In the photo-fabrication apparatus (1), the tilt angle of each micromirror in the DMD (32) is controlled by the computer (5). This can control the quantity of irradiation light for an irradiation region on the photosensitive member (9) corresponding to each micromirror, to perform an exposure in accordance with a three-dimensional shape of a desired object for a short time. The exposed photosensitive member (9) is developed by another apparatus.